



DOCUMENT CHANGE REQUEST

DCR number 650

Changes required for: N/A

Originator: J.K.Wong

Date: 2011/03/18

Date sent: 2011/03/18

Organisation: ESA/ESTEC

Status: IMPLEMENTED

Title: ESCC Qualified Manufacturers List REP006

Number: REP006

Issue: 4

Other documents affected:

Page:

(1) 5.2 Maintenance of Qualification

(2) 5.2.1 Technology Flow

(3) 5.2.1 (a) Basic Informaiton

Paragraph:

(1) 5.2 Maintenance of Qualification

(2) 5.2.1 Technology Flow

(3) 5.2.1 (a) Basic Informaiton

Original wording:

Proposed wording:

(1) Add 287B, Feb. 2011 to Feb. 2013 and CNES application no. 287B and this DCR to 3rd alinea of the table.

(2) Change "0605" to "0603" in first alinea under Scope and change "2,3 and 4" to "F2, F3 and F4" in 4th cell under Scope.

(3) Change "Protection :Silicon Nitride" to:


"- Passivation Layer: Silicon Nitride

- Protection: Epoxy + Silcone"

Justification:

(1) Extension of qualification

(2) and (3) updated informationas agreed with CNES and Vishay Sfernice.

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| Attachments: |
| N/A |
| Modifications: |
| N/A |
| Approval signature: |
|  |
| Date signed: |
| 2011-03-18 |